

1 Supporting Information

2 **A Monolithically Integrated, Intrinsically Safe, 10%**
3 **Efficient, Solar-Driven Water-Splitting System Based**
4 **on Active, Stable Earth-Abundant Electrocatalysts in**
5 **Conjunction with Tandem III-V Light Absorbers**
6 **Protected by Amorphous TiO₂ Films**

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25 **Materials and Methods**

26

27 Chemicals and materials

28

29 All materials were used as received, except where otherwise noted. H₂O with a
30 resistivity of 18.2 MΩ·cm was obtained from a Millipore de-ionized water system. A 1.0
31 M aqueous solution of KOH (semiconductor grade, Sigma-Aldrich, 99.99% trace metal
32 basis) was prepared for all electrochemical measurements. Inlet and outlet ports (PEEK,
33 0.30" ID and 0.0625" OD) used in prototypes were purchased from Upchurch Scientific
34 (Oak Harbor, WA 98277). The Ag-based conductive epoxy was obtained from
35 CircuitWorks from ITW Chemtronics (Kennesaw, GA 30152).

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37 Growth and preparation of III-V surfaces

38

39 The dual junction device was grown commercially (Sumika Electronic Materials,
40 Inc.) according to specifications determined by 1-D numerical simulation using
41 Helmholtz-Zentrum Berlin's AFORS-HET software. Planar III-V layers were grown
42 epitaxially by metal-organic chemical vapour deposition (MOCVD) on an n⁺-GaAs wafer
43 with a (100)-oriented polished surface (Si-doped, acceptor concentration of $1 \times 10^{19} \text{ cm}^{-3}$,
44 6" diameter).

45

46 Atomic layer deposition (ALD)

47

48 Films were deposited on the exposed p⁺-GaAs epilayer at 150 °C using an
49 Ultratech Fiji 200 plasma atomic-layer deposition (ALD) system. Prior to ALD, the
50 epitaxial surface was immersed for 30 s in 1.0 M KOH (aqueous solution of potassium
51 hydroxide pellets, semiconductor grade, 99.99% trace metals basis, Sigma-Aldrich),

52 rinsed with copious amounts of deionized H₂O, dried using a stream of N₂(g), and loaded
53 immediately thereafter into the ALD chamber. Each ALD cycle consisted of a 0.06 s
54 pulse of H₂O (18 MΩ·cm resistivity, Millipore), followed by a 0.25 s pulse of
55 tetrakis(dimethylamido)titanium (TDMAT, Sigma-Aldrich, 99.999%, used as received).
56 A 15 s purge under a constant 0.13 L min⁻¹ flow of research-grade Ar (g) was performed
57 between each precursor pulse. The base pressure during the TiO₂ growth was maintained
58 at ~0.1 Torr. ALD-TiO₂ films with thicknesses of 62.5 nm and 150 nm were used to
59 protect III-V surfaces.

60

61 Deposition of metal films and electrocatalysts

62

63 Ohmic contact to the n⁺-GaAs wafer was formed using a Ge-Au eutectic (20 nm
64 Ge/ 30 nm Au/ 15 nm Ni/ 100 nm Au) deposited by radio-frequency (RF) sputtering and
65 annealed under N₂(g) at 400 °C for 30 s using rapid thermal annealing. Solid-state
66 devices were formed by RF sputtering a metal grid of 100 nm thick Ni onto the p⁺-GaAs
67 surface. For all photoanode surfaces, an optically transparent nominally 2 nm thick Ni
68 film was deposited on TiO₂ using RF sputtering. Counter electrodes were formed by drop
69 casting Ni-Mo nanoparticles on Ni foil and annealing under forming gas (5% H₂, 95% N₂,
70 500 sccm, Airliquide) at 450 °C for 30 min, then cooling the electrodes to room
71 temperature under forming gas.¹ For the fully integrated prototype, a Ti/Ni-Mo
72 electrocatalyst was deposited using RF sputtering onto the Au-Ge back contact.

73

74 PEC assembly and device preparation

75

76 To measure the current density during photoelectrochemical operation, wafers
77 were cleaved into samples 0.5~1 cm² in area, and samples were mounted onto a Cu film
78 using a Ag-based conductive epoxy. Samples were then assembled into custom-made

79 compression cells that were equipped with fluorosilicone O-rings (0.0314 cm² Teflon,
80 0.34 cm² polymethyl methacrylate).

81 The prototype (Fig. 4a) consisted of: 1x PEC assemblies (10.0 mm x 10.0 mm), 2
82 x AHA-type NEOSEPTA anion exchange membrane (2 x 10 mm), 2 x acrylic chassis
83 that were 3-D printed, 1 x quartz window (15 mm in diameter), 8 x inlet and outlet ports
84 (PEEK, ID 0.75 mm, OD 1.5875 mm), and 16 x bolts (2-56" x 1") and/or epoxy (Loctite
85 9460, Hysol).

86 All transparent sections of the compression cells were covered using high-
87 performance black masking tape purchased from Thorlabs to prevent illumination of
88 electrochemically inactive surfaces.

89

90 AM 1.5 illumination and spectral response

91

92 A Xe lamp-based solar simulator and probe station was used to measure the solid-
93 state device performance. The light intensity was adjusted based on an NREL-calibrated
94 Si photovoltaic reference cell. For photoelectrochemical experiments, the illumination
95 intensity was calibrated by placing a Si photodiode (Thor Labs) in the Teflon
96 compression cell, in the same location occupied by the exposed area of the
97 photoelectrode. The Si photodiode was previously calibrated by measurement of the
98 short-circuit current-density value under AM 1.5 simulated sunlight at 100 mW cm⁻² (1-
99 Sun) of irradiance from a Xe arc lamp with an AM 1.5 filter. To obtain spectral response
100 data, monochromatic light was chopped at 17 Hz and was focused onto the sample
101 surface. An unchopped light-emitting diode (LED) was used to saturate the
102 AlGaAs/GaAs heterojunction (850 nm) or the InGaP homojunction (405 nm), to measure
103 the external quantum yield of the unsaturated subcell. Photoelectrochemical spectral
104 response data were obtained at the formal potential for water oxidation using a side-
105 facing chassis with a 0.34 cm² O-ring.

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107 Electrochemical measurements

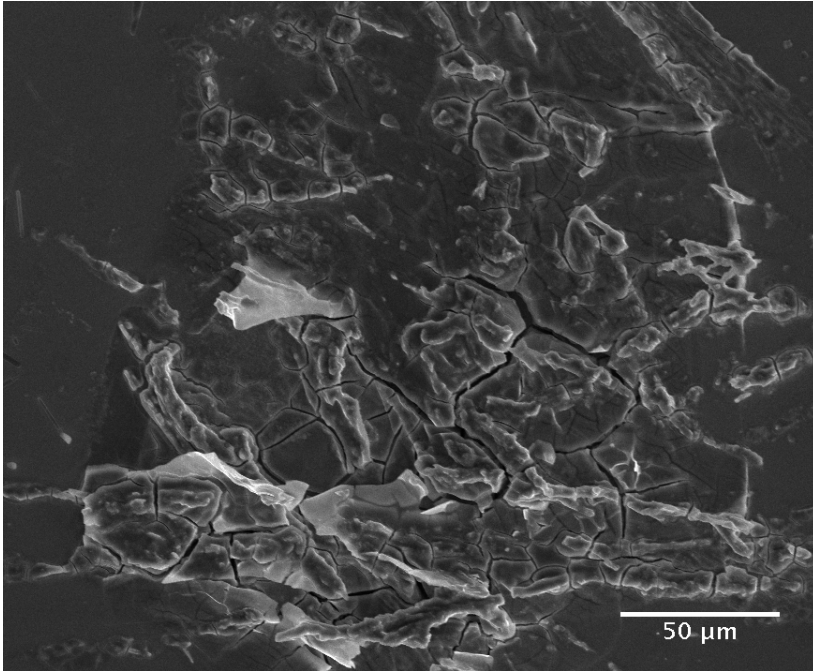
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109 A saturated calomel electrode (SCE, CH Instruments) was used as a reference
110 electrode for all three-electrode photoelectrochemical measurements, including spectral
111 response data. The pH of the 1.0 M KOH(aq) solution was 13.7, as measured using a
112 VWR SympHony SB70P Digital, Bench-model pH Meter. The equilibrium potential for
113 water oxidation in 1.0 M KOH(aq) was calculated to be 0.18 V vs. SCE. The active cell
114 area was determined by the size of the O-ring. For stability tests the custom-built Teflon
115 compression cell (Fig. 2b) O-ring size was 0.031 cm², and a liquid pumping system was
116 used to facilitate removal of bubbles from the sample surface and to decrease mass
117 transfer effects. All data for three-electrode electrochemical measurements in aqueous
118 solutions included compensation for solution series resistance as obtained from high-
119 frequency electrical-impedance measurements.

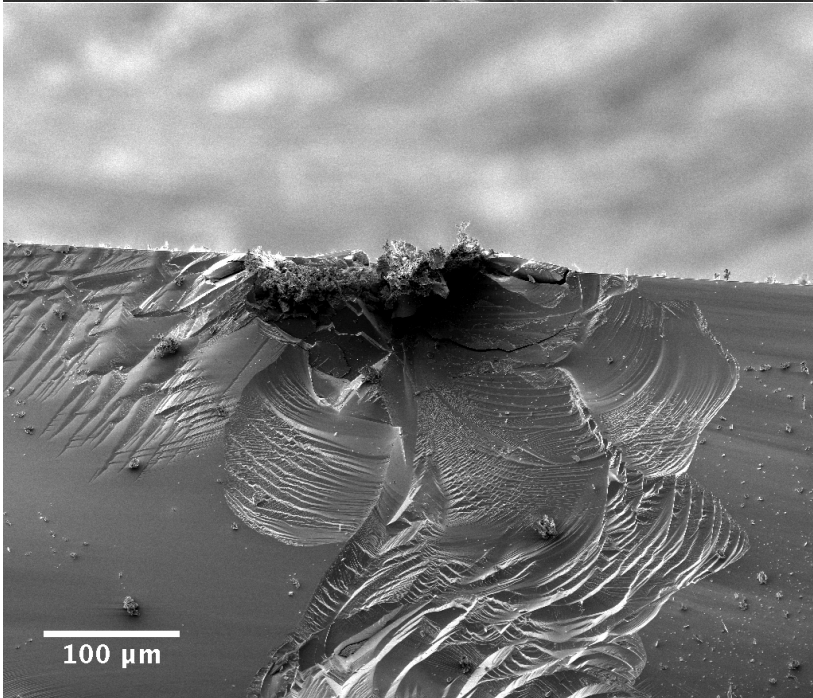
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121 Scanning electron microscopy (SEM) of device failure

122 For all samples, device failure was followed by a large increase in current density
123 caused by a breach in the TiO₂ protective film that led to photocorrosion of the III-V
124 layers. Lateral corrosion of the III-V device caused cracks in the TiO₂ that would
125 eventually lead to liftoff of the protection layer, as can be seen in Fig. S1a.



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127

128 **Figure S1** (a) SEM image of device failure after 6.5 hours of operation, showing
129 cracking of ALD-TiO₂ protection layer and corrosion of underlying III-V semiconductors.

130 (b) Side profile SEM of III-V corrosion.

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132 Eudiometer gas collection

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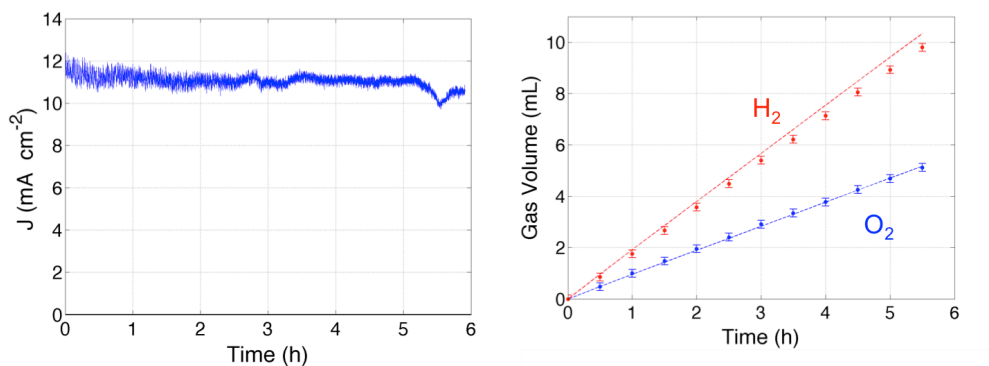
134 A custom-built polymethyl methacrylate (PMMA) chassis with anion exchange
135 membrane partitions was used to separate the gas products. A system of Teflon tubing at
136 the top of each chamber allowed $\text{H}_2(\text{g})$ and $\text{O}_2(\text{g})$ to flow into two eudiometers (0.05 mL
137 precision) that were filled with de-ionized water and suspended over large water
138 reservoirs. To prevent escape of hydrogen gas through the solution, the reservoir for
139 $\text{H}_2(\text{g})$ collection was saturated with pure $\text{H}_2(\text{g})$ for 30 min before operation..

140 The gas collection apparatus for the fully integrated prototype is shown in Fig. 4b.
141 The respective conduits transported gas products from the chassis chambers to the
142 eudiometers (inverted burette geometry), terminating at the water reservoir level to insure
143 that the chassis continuously operated at STP without any buildup of backpressure. High
144 precision manometers (Extech HD755) were used to sample the pressure variation inside
145 the eudiometers due to increasing gas volume every second. The pressure was measured
146 in inches water column, resulting in a well-defined meniscus velocity during the
147 experiment. A simple conversion factor between the eudiometer length and the
148 eudiometer volume allowed determination of the gas production rate (ml/s) from
149 measurement of the meniscus velocity (in/s). As produced gases were introduced to the
150 inverted burette and the water level decreased, the pressure of the gases inside the burette
151 increased. An additional conversion factor was applied to obtain the volume of produced
152 gas at STP, which was used to obtain the solar-to-hydrogen conversion efficiency in
153 Figure 4b.

154 The chassis in Figure 3a was also used for gas collection to determine the faradaic
155 efficiency of the system, as shown in Figure S2. The current density from spontaneous
156 water splitting was measured at zero external bias under 1.5 Sun illumination from a Xe
157 arc lamp with an AM 1.5 filter. This system was used to calculate the expected gas
158 production. Measurements were made at regular intervals for over a 5 h period. The
159 Faradaic efficiency was 100% for $\text{O}_2(\text{g})$, and was 90% for $\text{H}_2(\text{g})$ collection, due to

160 hydrogen leaks in the chassis and tubing. The final products were analyzed using gas
161 chromatography (GC) by thermal conductivity detectors (TCD), and the composition of
162 the products was confirmed as well with a $\sim 2\%$ gas crossover rate.

163



164

165 **Figure S2** (a) Short-circuit photocurrent density $J_{\text{photo, short}}$ under 1.5 Suns using AM 1.5
166 illumination. (b) Gas volume was measured at regular intervals, and is compared to
167 expected gas production (dotted lines) based on total charge passed.

168

169 Spectroscopic ellipsometry

170

171 Complex refractive index (n, k) data for films of as-grown TiO_2 on Si were
172 obtained using spectroscopic ellipsometry. The ellipsometric data were acquired using a
173 J.A. Woolam V-VASE system. The non-absorbing ($k \sim 0$) portion of the data was fit using
174 a Cauchy model that assumed a $\text{TiO}_2/\text{SiO}_2$ bilayer structure on Si. The TiO_2 n, k values
175 were extracted from a point-by-point fit, using fixed Cauchy and film-thickness
176 parameters.

177

178 Optical modeling

179

180 Reflection spectra of tandem III-V substrates with TiO_2 coatings of different
181 thicknesses were calculated by solving the transfer matrix (Figure S3a). Refractive

182 indices of all the layers were obtained or interpolated from experimental data at
183 <http://www.ioffe.ru/SVA/NSM/nk/>. The refractive index of protective TiO₂ from atomic
184 layer deposition was obtained from spectroscopic ellipsometry. The Matlab function
185 (*multidiel*), developed by Sophocles J. Orfanidis from Rutgers University, was used to
186 calculate the reflection responses of the isotropic lossy multilayer dielectric structures².
187 The structural information used in the calculation is shown in Figure 1a.

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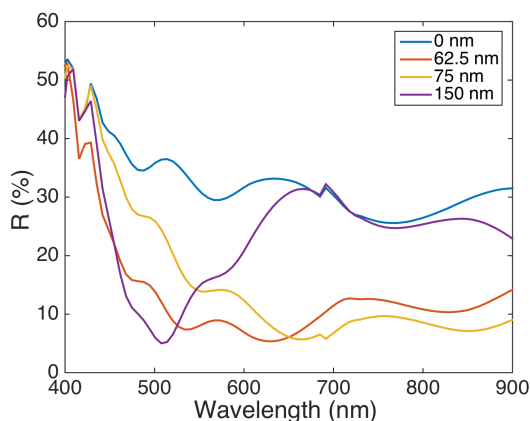
189 UV-vis reflectance and transmittance measurement

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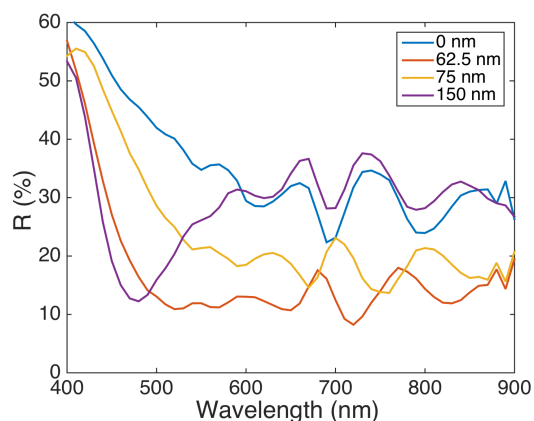
191 The optical reflectance of the TiO₂ and Ni metal-coated TiO₂/III-V tandem
192 substrates (Figure S3b) were determined by using an integrating sphere at normal
193 incidence (Agilent Cary 5000 UV-Vis spectrometer). The absorptance (A) of TiO₂-
194 coated tandem junction substrates was calculated from the measured total reflectance (R)
195 and transmittance (T) of the electrode as $A = 1 - R - T$. All optical measurements were
196 performed in air on fresh samples without chemical/electrochemical treatment. These
197 results were used to select a TiO₂ anti-reflection coating thickness that increased current
198 density in the current-limiting InGaP cell while still providing a thick conformal coverage
199 of to serve as a protection layer.

200

201



202



203 **Figure S3.** Reflectance of GaAs/InGaP structure with varying thicknesses of TiO₂ that
204 serves as a single-layer anti-reflection coating. (a) Optical model. (b) Integrating sphere.

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207 **Discussion**

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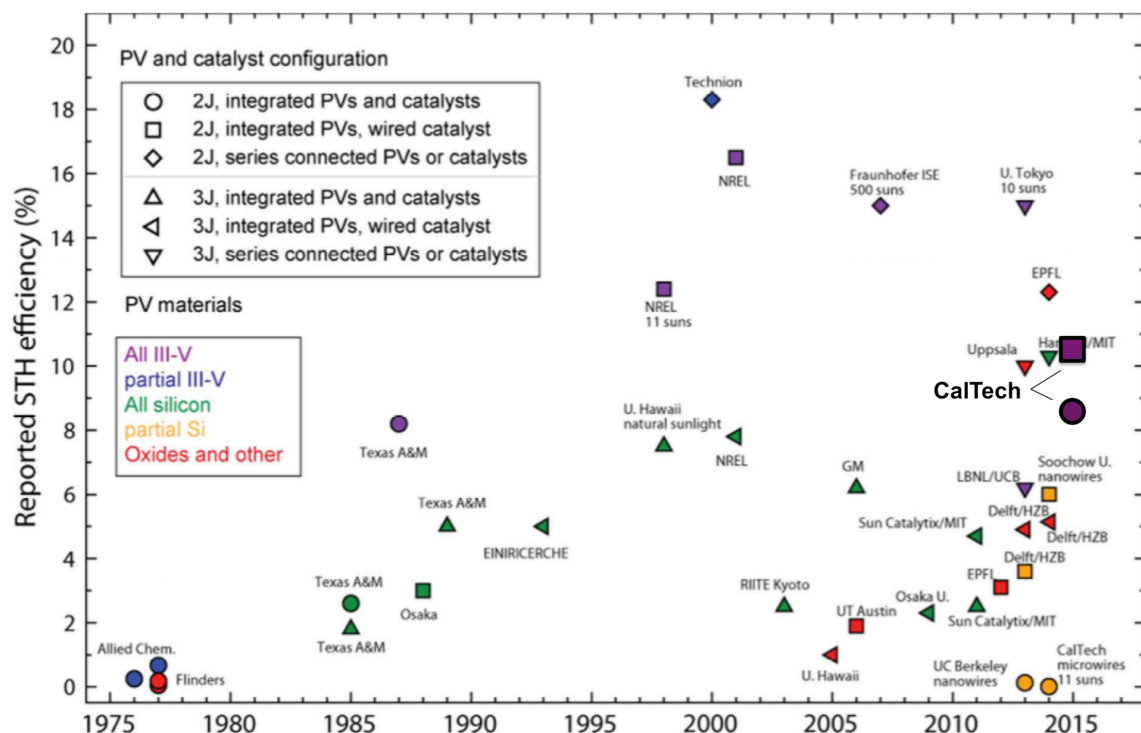
209 External quantum yields of solid-state and PEC cells

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211 The EQE of solid state and photoelectrochemical cells, shown in Fig. 1a and Fig.
212 2a, are not optimal and have room for improvement in future designs. Dual junction
213 GaAs/InGaP devices in literature include double layer anti-reflection coatings (DLARCs)
214 with optimized indices of refraction and thicknesses for a III-V layer stack. Many of these
215 DLARCs are unstable in alkaline electrolyte or are unsuitable for operation in a planar
216 PEC device. The solid-state measurements reported herein were obtained without any
217 surface treatment or anti-reflection coating, which results in reflection losses of ~30% for
218 most wavelengths in the solar spectrum. The behavior of the photoelectrode benefits
219 slightly from being submerged in solution that has a higher index of refraction than air, as
220 well as from the TiO₂ coating which acts as a (sub-optimal) single-layer anti-reflection
221 coating (ARC). A second cause of reduced EQE is parasitic absorption by the 7 nm GaAs
222 contact layer, which absorbs photons that have energies above the band gap of GaAs,
223 1.42 eV. The presence of this layer was needed to obtain facile for hole conduction
224 through the TiO₂ protection layer, since ALD-TiO₂ grown on window layers that
225 contained exposed aluminum did not exhibit the desired electrical properties. Simulations
226 indicated that parasitic absorption of short wavelength light was especially detrimental to
227 the performance of the high bandgap InGaP cell.

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229



230

231 **Figure S4.** A compilation of reported solar-to-hydrogen (STH) efficiencies.³ New entries
 232 (bold) indicate the efficiency of the 2J, integrated, III-V devices reported in the main text.

233

234 Operational Criteria for Safe, Efficient Electrolyzers:

235 Commercial electrolyzers must meet several criteria to be considered safe and
 236 reliable for operation and sale into the marketplace. They must be intrinsically safe, and
 237 not produce a flammable, potentially explosive mixture of H₂(g) and O₂(g) in the reactor
 238 at any point in space or time, especially because the reactor contains active catalysts for
 239 the recombination of the gases and is operating in the presence of light and heat.

240 Electrolyzers must be able to withstand pressure differentials without undesirable
 241 crossover of gases or flooding and flow of the liquid electrolyte across the membrane
 242 separator, because the stoichiometry of the evolved H₂ and O₂ is 2:1. The membrane
 243 must be able to hold back pressure because a pressure differential is required to
 244 beneficially collect the H₂(g) in a pipeline, as opposed to evolving the gas at atmospheric

245 pressure in a laboratory demonstration device. The photoelectrochemical systems
246 described herein satisfy these same design and operational constraints in full.

247 Both modeling/simulation results and experimental data have shown that
248 electrolyzers operated in solutions buffered to near-neutral pH are inefficient and/or not
249 intrinsically safe. For example, operation of a membrane-free near-neutral pH a-Si:H
250 device with ITO protective layers and earth-abundant, high overpotential electrocatalysts
251 at $\eta_{\text{STH}} = 3.2\%$ produced 10% O₂(g) in the cathode chamber and up to 40% H₂(g) in the
252 anode chamber, presenting an explosion hazard.⁴ Introduction of a membrane was shown
253 to yield a large reduction in the system efficiency and resulted in significant pH gradients
254 near the electrode surfaces. Further modeling and simulation has shown that steady-state
255 operation in such a geometry even in buffered solutions will result in pH gradients
256 between the anode and cathode that produce local pH changes near the electrode surfaces,
257 due to the consumption of protons associated with evolution of H₂(g) from water and
258 concomitant production of protons associated with production of O₂(g) from H₂O.^{4,5} The
259 overpotentials associated with the pH gradients and electro dialysis exceeded the
260 combined overpotentials associated with the oxygen-evolving and hydrogen-evolving
261 electrocatalysts, precluding the construction of an efficient (photo)electrolysis system.
262 Further modeling and simulation efforts have shown that active convection by bubble
263 evolution, for example, can minimize the formation of pH gradients but results in the loss
264 of intrinsic safety, due to the concomitant co-evolution of stoichiometric, potentially
265 explosive, mixtures of H₂(g) and O₂(g) at atmospheric pressure in the reaction vessel, in
266 the presence of active catalysts for the recombination of these gases as well as in the
267 presence of light and heat.⁵

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269

270 **Video**

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272 Full operation of the monolithically integrated 1 cm² prototype performing unassisted
273 water splitting is available for download along with this publication.

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